

AF 12851  
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RESPONSE UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 2851

03560.002558

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
Yuji SUDOH et al. ) : Examiner: H. Nguyen  
Application No.: 09/532,022 ) : Group Art Unit: 2851  
Filed: March 21, 2000 ) :  
For: EXPOSURE APPARATUS AND A )  
DEVICE MANUFACTURING METHOD :  
WHICH KEEP TEMPERATURE OF A )  
DIAPHRAGM OF A PROJECTION :  
OPTICAL SYSTEM SUBSTANTIALLY )  
CONSTANT : August 3, 2004

**Mail Stop AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Do not enter.

8/16/04

AMENDMENT AFTER FINAL ACTION

HN

Sir:

In response to the final Official Action dated May 7, 2004, please amend the above-identified application as follows, pursuant to 37 C.F.R. § 1.116: